

This Page Is Inserted by IFW Operations
and is not a part of the Official Record

BEST AVAILABLE IMAGES

Defective images within this document are accurate representation of
The original documents submitted by the applicant.

Defects in the images may include (but are not limited to):

- BLACK BORDERS
- TEXT CUT OFF AT TOP, BOTTOM OR SIDES
- FADED TEXT
- ILLEGIBLE TEXT
- SKEWED/SLANTED IMAGES
- COLORED PHOTOS
- BLACK OR VERY BLACK AND WHITE DARK PHOTOS
- GRAY SCALE DOCUMENTS

IMAGES ARE BEST AVAILABLE COPY.

**As rescanning documents *will not* correct images,
please do not report the images to the
Image Problem Mailbox.**

THIS PAGE BLANK (USPTO)



PCT/AU99/00894

REC'D 02 DEC 1999

WIPO PCT

**PRIORITY
DOCUMENT**

SUBMITTED OR TRANSMITTED IN
COMPLIANCE WITH RULE 17.1(a) OR (b)

Patent Office
Canberra

#8
PRIVILEGE
25/02
JJS

I, LEANNE MYNOTT, TEAM LEADER EXAMINATION SUPPORT AND SALES hereby certify that annexed is a true copy of the Provisional specification in connection with Application No. PP 7022 for a patent by SILVERBROOK RESEARCH PTY LTD filed on 09 November 1998.

WITNESS my hand this
Twenty-sixth day of November 1999

LEANNE MYNOTT
TEAM LEADER EXAMINATION
SUPPORT AND SALES



AUSTRALIA
Patents Act 1990

PROVISIONAL SPECIFICATION

Applicant(s) :

SILVERBROOK RESEARCH PTY LTD



Invention Title: Micromechanical Device and Method (IJ460^I)

The invention is described in the following statement:



MECHANICAL DEVICE AND METHOD (IJ466^I)

Field of the Invention

The present invention relates to the field of fluid ejection devices such as ink jet printers and, in particular, discloses the utilization of a poker on the end of the ejection panel.

Background of the Invention

Many different types of printing have been invented, a large number of which are presently in use. The known forms of printers have a variety of methods for marking the print media with a relevant marking media. Commonly used forms of printing include offset printing, laser printing and copying devices, dot matrix type impact printers, thermal paper printers, film recorders, thermal wax printers, dye sublimation printers and ink jet printers both of the drop on demand and continuous flow type. Each type of printer has its own advantages and problems when considering cost, speed, quality, reliability, simplicity of construction and operation etc.

In recent years, the field of ink jet printing, wherein each individual pixel of ink is derived from one or more ink nozzles has become increasingly popular primarily due to its inexpensive and versatile nature.

Many different techniques on ink jet printing have been invented. For a survey of the field, reference is made to an article by J Moore, "Non-Impact Printing: Introduction and Historical Perspective", Output Hard Copy Devices, Editors R Dubeck and S Sherr, pages 207 - 220 (1988).

Ink Jet printers themselves come in many different types. The utilisation of a continuous stream ink in ink jet printing appears to date back to at least 1929 wherein US Patent No. 1941001 by Hansell discloses a simple form of continuous stream electro-static ink jet printing.

US Patent 3596275 by Sweet also discloses a process of a continuous ink jet printing including the step wherein the

ink jet stream is modulated by a high frequency electro-static field so as to cause drop separation. This technique is still utilized by several manufacturers including Elmjeter and Scitex (see also US Patent No. 3373437 by Sweet et al)

5 Piezo-electric ink jet printers are also one form of commonly utilized ink jet printing device. Piezo-electric systems are disclosed by Kyser et. al. in US Patent No. 3946398 (1970) which utilizes a diaphragm mode of operation, by Zolten in US Patent 3683212 (1970) which discloses a
10 squeeze mode of operation of a piezo electric crystal, Stemme in US Patent No. 3747120 (1972) discloses a bend mode of piezo-electric operation, Howkins in US Patent No. 4459601 discloses a Piezo electric push mode actuation of the ink jet stream and Fischbeck in US 4584590 which
15 discloses a sheer mode type of piezo-electric transducer element.

Recently, thermal ink jet printing has become an extremely popular form of ink jet printing. The ink jet printing techniques include those disclosed by Endo et al in
20 GB 2007162 (1979) and Vaught et al in US Patent 4490728. Both the aforementioned references disclosed ink jet printing techniques rely upon the activation of an electrothermal actuator which results in the creation of a bubble in a constricted space, such as a nozzle, which
25 thereby causes the ejection of ink from an aperture connected to the confined space onto a relevant print media. Printing devices utilizing the electro-thermal actuator are manufactured by manufacturers such as Canon and Hewlett Packard.

30 As can be seen from the foregoing, many different types of printing technologies are available. Ideally, a printing technology should have a number of desirable attributes. These include inexpensive construction and operation, high speed operation, safe and continuous long term operation
35 etc. Each technology may have its own advantages and

disadvantages in the areas of cost, speed, quality, reliability, power usage, simplicity of construction operation, durability and consumables.

Recently, the present applicant has disclosed for
5 example, an Australian Provisional Patent No. PP6534
entitled "Micromechanical Device and Method (IJ46a)", filed
16 October 1998 a new form of ink jet printer containing an
ink ejection mechanism that includes a thermal bend
10 actuator actuated in an external ambient environment which
is interconnected with a paddle mechanism utilised for the
ejection of ink.

Unfortunately, in the aforementioned ink jet
printing arrangement as in most ink jet printing
arrangements, there is a tendency of the ink ejection
15 nozzles to dry out over time which can result in the build
up of crustaceans etc. Further, there is also the
propensity of such devices to become clogged by other means
such as foreign bodies in the ink or paper fibres, material
etc. around the ink ejection nozzle.

20 Further, in the aforementioned arrangement, there
is a significant gap left in one wall of the ink ejection
chamber, the gap being required and utilized by the
movement of the thermal actuator up and down during an
ejection cycle. Unfortunately, the provision of the slot
25 may cause ink flow to wick out of the nozzle chamber and
along the thermal actuator which can cause problems with
ink loss due to wicking. Such ink loss is generally
undesirable.

Summary of the Invention

30 In accordance with a first aspect of the present
invention, there is provided a liquid ejection apparatus
comprising: a nozzle chamber having an aperture defined in
one wall thereof for the ejection of fluid out of the
aperture; an ink supply channel interconnected with the
35 nozzle chamber; a moveable paddle actuator operable to
eject ink from the nozzle chamber the paddle actuator

having a projecting part which, upon activation of the actuator is caused to move towards the nozzle aperture.

The projecting part, upon activation of the actuator, moves through the plane of the aperture and can be located
5 concentrically with the nozzle aperture.

The liquid ejection aperture can be formed utilizing the deposition and etching of a series of layers and the projecting part can comprise a hollow cylindrical column.

The hollow cylindrical column preferably can include
10 an end adjacent the aperture which can be chemically mechanically planarized during the formation of the aperture.

The actuator can comprise a thermal bend actuator conductively heated so as to cause movement of the paddle.

15 The projecting part can be located substantially centrally on the paddle.

In accordance with a further aspect of the present invention, there is provided in a liquid ejection nozzle arrangement having a chamber from which liquid is ejected
20 from a nozzle aperture interconnected with the chamber by means of movement of a liquid ejection paddle, a method of improving the operational characteristics of the arrangement comprising the steps of: locating a projecting part on the moveable paddle, the projecting part undergoing
25 movement towards the nozzle aperture upon activation of the liquid ejection paddle to eject fluid.

The projection part preferably can include an end portion which moves through the plane of an outer rim of the aperture upon activation of the liquid ejection paddle.

30 Brief Description of the Drawings

Notwithstanding any other forms which may fall within the scope of the present invention, preferred forms of the invention will now be described, by way of example only, with reference to the accompanying drawings in which:

Fig. 1 - 3 illustrates schematically the operational principles of the preferred embodiments;

Fig. 4 is a side perspective view, partly in section, of a single nozzle arrangement of the preferred embodiment;

5 Fig. 5 illustrates a side perspective of a single nozzle including the shroud arrangement; and

Fig. 6 - 8 illustrates the principles of chemical, mechanical planarization utilized in the formation of the preferred embodiment.

10 Description of Preferred Embodiments

In the preferred embodiment, a paddle is formed with a "poker" device attached in a central portion thereof such that, during movement of the paddle, the poker device pokes any unwanted foreign body or material which should
15 congregate around the nozzle, out of the nozzle. The poker can be formed during fabrication of the ink ejection nozzle arrangement by means of a chemical mechanical planarization step with, preferably, the formation being a byproduct of the normal formation steps for forming the ink ejection
20 nozzle on arrangement on a semi-conductor wafer utilizing standard MEMS processing techniques.

Additionally, in order to restrict the amount of wicking and the opportunities for wicking, an actuator slot guard is provided, formed on the bend actuator itself,
25 closely adjacent to the actuator slot so as to restrict the opportunities for flow of fluid out of the nozzle chamber due to surface tension effects.

Turning now to Fig. 1 to Fig. 3 there will now be explained the operational principles of the preferred
30 embodiment. In Fig. 1, there is illustrated a nozzle arrangement 1 which is formed on the substrate 2 which can comprise a semi-conductor substrate or the like. The arrangement 1 includes a nozzle chamber 3 which is normally filled with ink so as to form a meniscus 4 which surrounds
35 a nozzle rim 5. A thermal bend actuator device 6 is attached to post 7 and includes a conductive heater portion

9 which is normally balanced with a corresponding layer 10 in thermal equilibrium. The actuator 6 passes through a slot in the wall 12 of the nozzle chamber and inside forms a nozzle ejection paddle 13. On the paddle 13 is formed a "poker" 15 which is formed when forming the walls of the nozzle chamber 3. Also formed on the actuator 6 is an actuator slot protection barrier 16. An ink supply channel 17 is also formed through the surface of the substrate 2 utilizing highly anisotropic etching of the substrate 2. During operation, ink flows out of the nozzle chamber 3 so as to form a layer 19 between the slot in the wall 12 and the actuator slot protection barrier 16. The protection barrier is profiled to substantially mate with the slot but to be slightly spaced apart therefrom so that any meniscus eg. 19 is of small dimensions.

Next, as illustrated in Fig. 2, when it is desired to eject a drop from the nozzle chamber 3, the bottom conductive thermal actuator 9 is heated electrically so as to undergo a rapid expansion which in turn results in the rapid upward movement of the paddle 13. The rapid upward movement of the paddle 13 results in ink flow out of the nozzle so as to form bulging ink meniscus 4. Importantly, the movement of the actuator 6 results in the poker 15 moving up through the plane of the nozzle rim so as to assist in the ejection of any debris which may be in the vicinity of the nozzle rim 5.

Further, the movement of the actuator 6 results in a slight movement of the actuator slot protection barrier 16 which maintains substantially the small dimensioned meniscus 19 thereby reducing the opportunity for ink wicking along surfaces. Subsequently, the conductive heater 9 is turned off and the actuator 6 begins to rapidly return to its original position. The forward momentum of the ink around meniscus 4 in addition to the backflow due to return movement of the actuator 6 results in a general necking and breaking of the meniscus 4 so as to form a drop.

The situation a short time later is as illustrated in Fig. 3 where a drop 20 proceeds to the print media and the meniscus collapses around poker 15 so as to form menisci 22, 23. The formation of the menisci 22, 23 result in a high surface tension pressure being exerted in the nozzle chamber 3 which results in ink being drawn into the nozzle chamber 3 via ink supply channel 17 so as to rapidly refill the nozzle chamber 3. The utilization of the poker 15 increases the speed of refill in addition to ensuring that no air bubble forms within the nozzle chamber 3 by means of the meniscus attaching to the surface of the nozzle paddle 13 and remaining there. The poker 15 ensures that the meniscus eg. 22, 23 will run along the poker 15 so as to refill in the nozzle chamber. Additionally, the area around the actuator slot barrier 16 remains substantially stable minimizing the opportunities for wicking therefrom.

Turning now to Fig. 4 there is illustrated a side perspective view of a single nozzle arrangement 1 shown in sections. Fig. 5 illustrates a side perspective view of a single nozzle including a protective shroud 30. The central poker 15 and aperture card 16 are as previously discussed. The construction of the arrangement of Figs. 4 and 5 can be as a result of the simple modification of deep mask steps utilized in the construction of the nozzle arrangement in Australian Provisional Patent Application PP6534 (the contents of which are specifically incorporated by cross-reference) so as to include the poker 15 and guard 16. The poker and guard are constructed primarily by means of a chemical mechanical planarization step which is illustrated schematically in Fig. 6 to Fig. 8. The poker 15 and guard 16 are constructed by depositing a surface layer 32 on a sacrificial layer 31 which includes a series of etched vias eg. 33. Subsequently, as illustrated in Fig. 7, the top layer is chemically and mechanically planarized off so as to leave the underlying structure 35 which is attached to lower structural layers 36. Subsequently, as illustrated in Fig. 8, the sacrificial

layer 31 is etched away leaving the resulting structure as required.

5 It would be appreciated by a person skilled in the art that numerous variations and/or modifications may be made to the present invention as shown in the specific embodiment without departing from the spirit or scope of the invention as broadly described. The present embodiment is, therefore, to be considered in all respects to be illustrative and not restrictive.

We Claim:

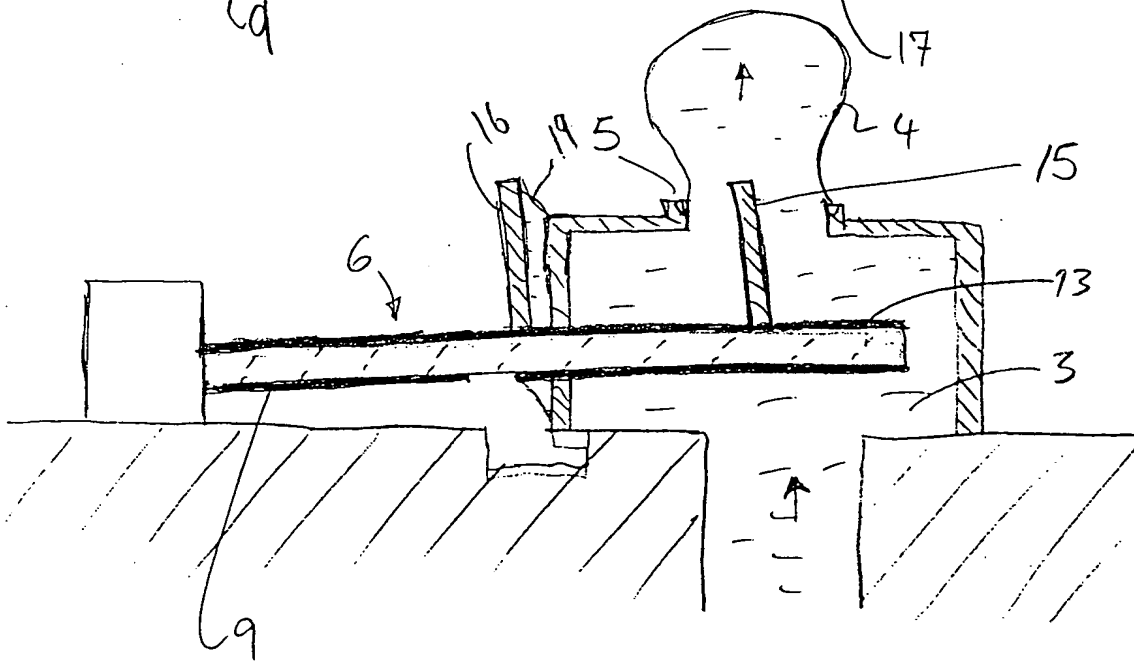
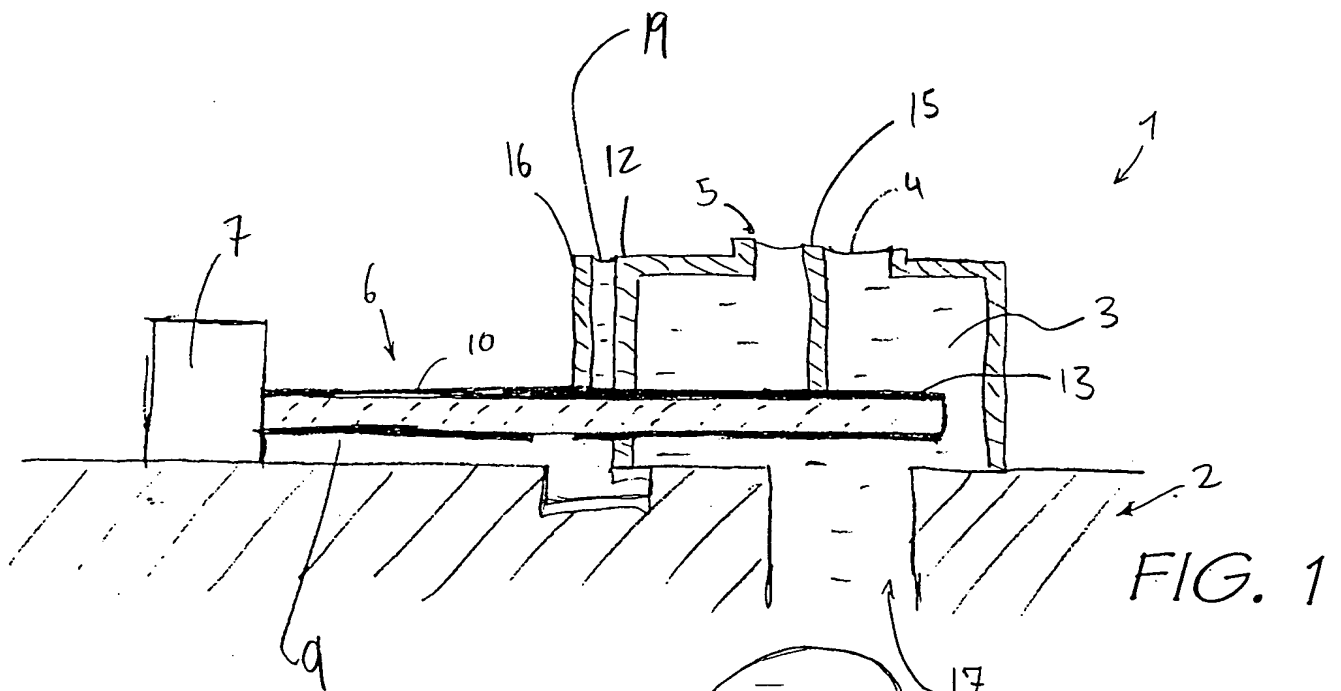
1. A liquid ejection apparatus comprising:
a nozzle chamber having an aperture defined in
one wall thereof for the ejection of fluid out of said
5 aperture;
an ink supply channel interconnected with said
nozzle chamber;
a moveable paddle actuator operable to eject ink
from said nozzle chamber said paddle actuator having a
10 projecting part which, upon activation of said actuator is
caused to move towards said nozzle aperture.
2. A liquid ejection apparatus as claimed in claim 1
wherein said projecting part, upon activation of said
actuator, moves through the plane of said aperture.
- 15 3. A liquid ejection apparatus as claimed in any
previous claim wherein said projecting part is located
concentrically with said nozzle aperture.
4. A liquid ejection apparatus as claimed in any
previous claim wherein said liquid ejection aperture is
20 formed utilizing the deposition and etching of a series of
layers and said projecting part comprises a hollow
cylindrical column.
5. A liquid ejection apparatus as claimed in claim 4
wherein said hollow cylindrical column includes an end
25 adjacent said aperture which is chemically mechanically
planarized during the formation of said aperture.
6. A liquid ejection apparatus as claimed in any
previous claim wherein said actuator comprises a thermal
bend actuator conductively heated so as to cause movement
30 of said paddle.
7. A liquid ejection apparatus as claimed in any
previous claim wherein said projecting part is located
substantially centrally on said paddle.
8. In a liquid ejection nozzle arrangement having a
35 chamber from which liquid is ejected from a nozzle aperture

interconnected with said chamber by means of movement of a liquid ejection paddle, a method of improving the operational characteristics of said arrangement comprising the steps of:

5 locating a projecting part on said moveable paddle, said projecting part undergoing movement towards said nozzle aperture upon activation of said liquid ejection paddle to eject fluid.

9. A method as claimed in claim 8 wherein said
10 projection part includes an end portion which moves through the plane of an outer rim of said aperture upon activation of said liquid ejection paddle.

10 A method as claimed in any previous claim 8 or 9
15 wherein said projecting part is arranged substantially concentrically with the nozzle aperture.



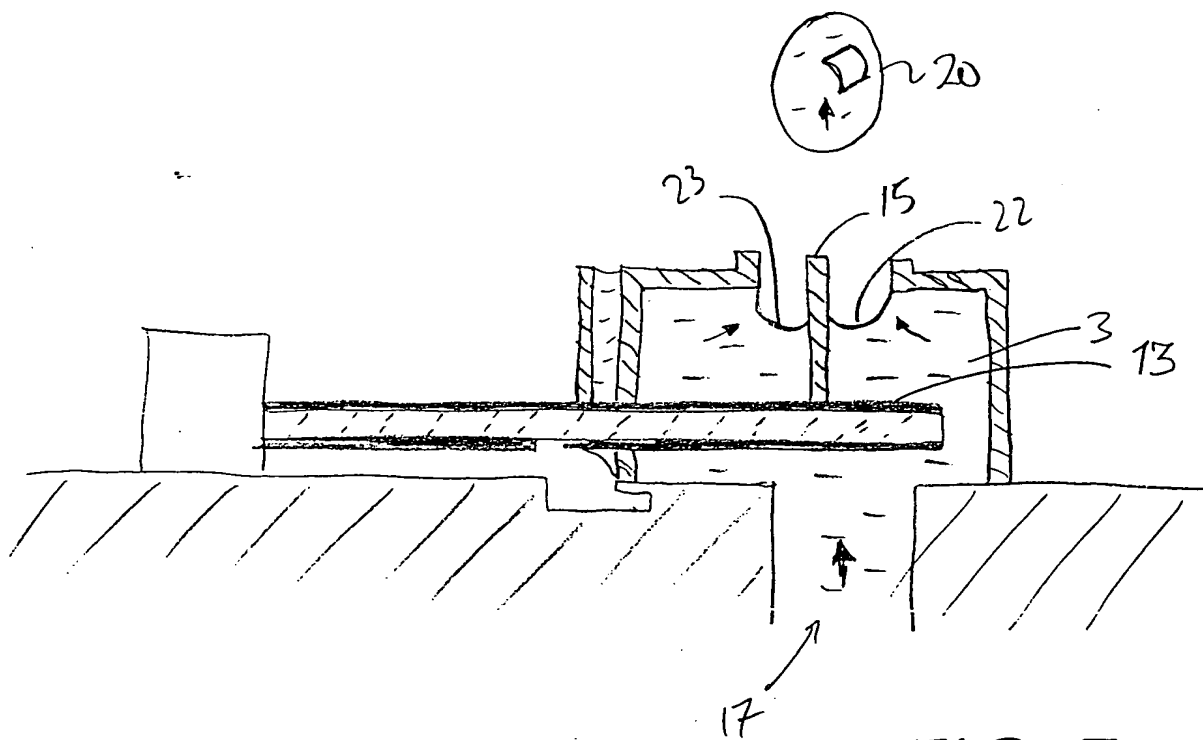
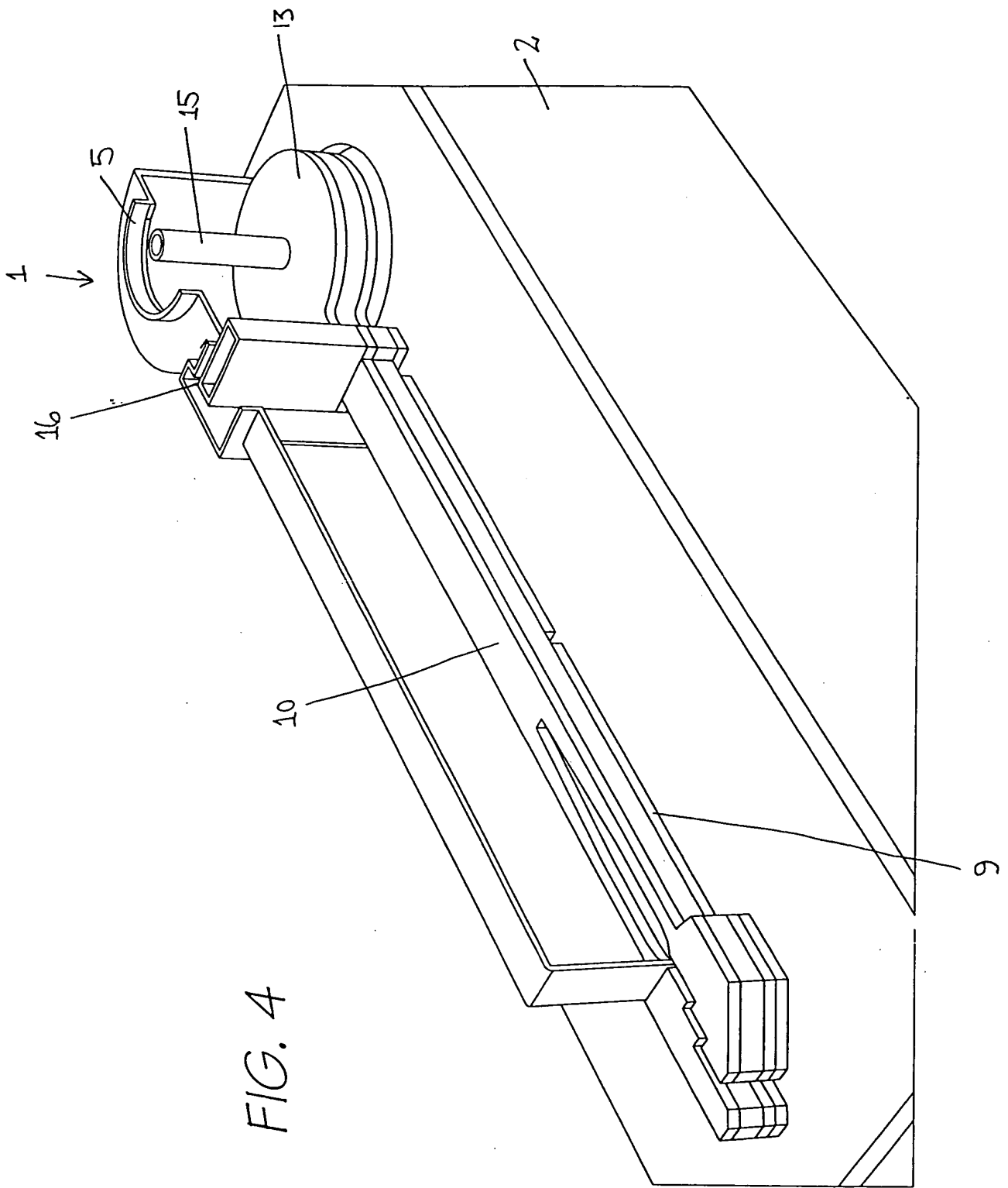


FIG. 3



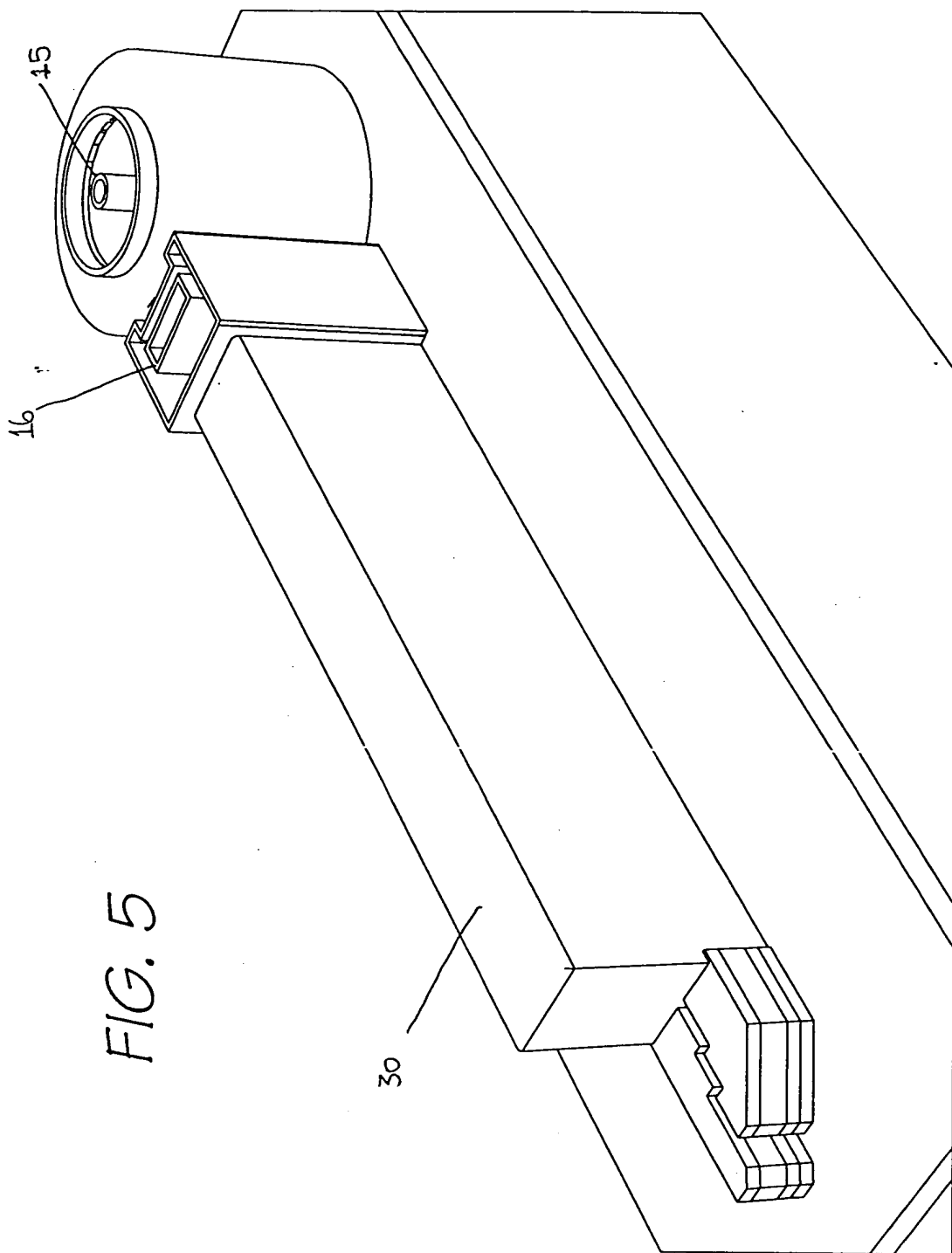


FIG. 5

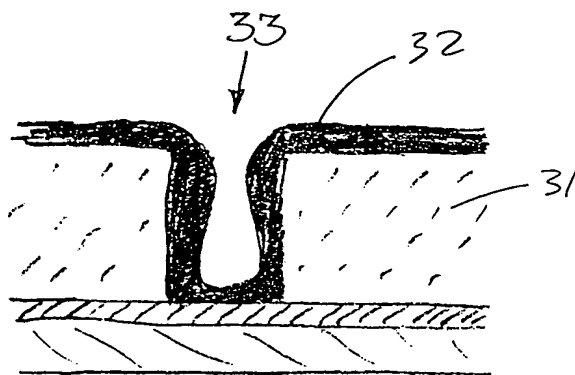


FIG. 6

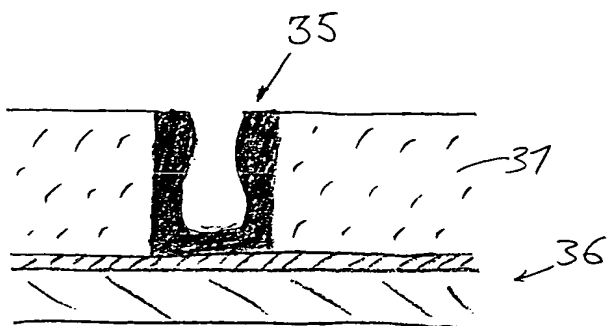


FIG. 7

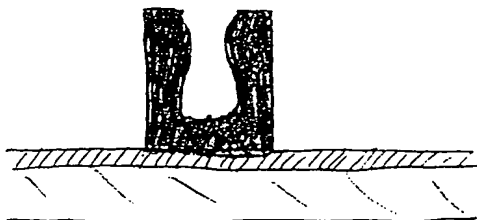


FIG. 8

ABSTRACT

A liquid ejection apparatus comprising: a nozzle chamber having an aperture defined in one wall thereof for the ejection of fluid out of the aperture; an ink supply
5 channel interconnected with the nozzle chamber; a moveable paddle actuator operable to eject ink from the nozzle chamber the paddle actuator having a projecting part which, upon activation of the actuator is caused to move towards the nozzle aperture. The projecting part, upon activation
10 of the actuator, moves through the plane of the aperture. The projecting part can be located concentrically with the nozzle aperture. The liquid ejection aperture can be formed utilizing the deposition and etching of a series of layers and the projecting part can comprise a hollow cylindrical
15 column. The hollow cylindrical column preferably can include an end adjacent the aperture which can be chemically mechanically planarized during the formation of the aperture.